



BAK UNI Vacuum Thin Film Evaporation System from Evatec

Responsible

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System Description

Fully automatic vacuum E-beam evaporation batch deposition tool with **Khan Server and EBS500**.

Custom E-Gun ESQ212B with 8 pockets using [20cc liners](#)

High voltage power supply EHV500 10kV/10kW

Filament current power supply EFS500 0-60A

Base pressure $\leq 2.0E-6$ mbar in ~ 45 minutes, $\leq 2.0E-7$ mbar overnight or $\leq 5.0E-7$ mbar overnight weekend.

Sample size:

Small chips, up to 9x 4inch wafers or 5x 6inch wafers or 1x 8inch wafers.

Materials:

Pocket 1: Cr

Pocket 2: Ti

Pocket 3: Al/Al₂O₃

Pocket 4: Ni/Pd

Pocket 5: Au/Ag

Pocket 6 : Cu

Pocket 7 : Pt

Pocket 8: SiO₂/ Si

Processes for several other materials are available on request.

New materials from [this list](#) can be evaporated, please ask the tool responsible.

Training and booking

Please use [Openiris](#) to ask for training, bookings or to submit issues with the tool.

Important

To reduce costs, starting with 2025, Au and Pt are charged separately.

100nm Au requires ~ 2.5 g and costs ~ 350 CHF.

100nm Pt requires ~ 4 g and costs ~ 200 CHF

Always load as many samples as possible to optimize material consumption!